

DEC 21 2004

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/075,193  
Filing Date ..... February 13, 2002  
Inventor ..... Shenlin Chen et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... Huynh, Y.  
Attorney's Docket No. .... MI22-1927  
Title: Methods of Forming a Capacitor Structure

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: October 21, 2003By: Jennifer J. TaylorJennifer J. Taylor, Ph.D.  
Reg. No. 48,711

Form PTO-1449

ATTY. DOCKET NO.  
M123-1927SERIAL NO.  
10/075,193LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
Shenlin Chen et al.FILING DATE  
February 13, 2002GROUP  
2813

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	2001/0003053 A1	05-2001	Kwok et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		

EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.